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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Michael L. McSwiney et al.

Serial No.: 10/764,193

Filed: January 23, 2004

For: Forming a Silicon  
Nitride Film

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Art Unit: 1792

Examiner: Renee R. Berry

Atty Docket: ITL.1056US  
P17793

Assignee: Intel Corporation

Mail Stop **Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**REPLY TO OFFICE ACTION**

Sir:

In response to the office action mailed October 9, 2007, please amend the above-referenced patent application as follows:

Date of Deposit: January 7, 2008

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Cynthia L. Hayden*  
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